

**DRAFT**

Appl. No. 10/009.910  
 Amdt. Dated \_\_\_\_\_  
 Reply to Office Action of August 21, 2003

Attorney Docket No. 81839.0107  
 Customer No.: 26021

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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:  
 Makoto IIDA et al.  
 Serial No: 10/009,910  
 Confirmation No.: 7347  
 Filed: December 12, 2001  
 For: SILICON WAFER, SILICON  
 EPITAXIAL WAFER, ANNEAL  
 WAFER AND METHOD FOR  
 PRODUCING THEM

Art Unit: 1765  
 Examiner: Matthew J. Song

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**AMENDMENT**

Mail Stop Non-Fee Amendment  
 Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

Dear Sir:

In conjunction with the Request for Continued Examination (RCE) filed on October 8, 2003 in connection with the above-identified application, and pursuant to a phone conference with the Examiner, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.

## HOGAN &amp; HARTSON L.L.P.

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**TELECOPY/FACSIMILE COVER LETTER**

**TO:** Examiner Matthew J. Song  
U.S. Patent and Trademark Office  
Group Art Unit 1765

**FROM:** John P. Scherlacher  
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**DATE:** October 14, 2003

**TIME:** \_\_\_\_\_

**TOTAL NO. OF PAGES, INCLUDING COVER:** 7

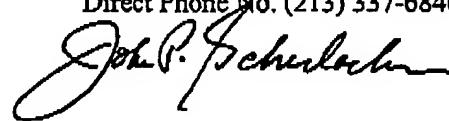
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**MESSAGE RE: U.S. Patent Application Serial No. 10/009,910 filed December 12, 2001**

**Applicant: Makoto IIDA et al; For: SILICON WAFER, SILICON EPITAXIAL WAFER, ANNEAL WAFER AND METHOD FOR PRODUCING THEM**

Pursuant to our recent phone conversation, and in connection with an RCE filed October 8, 2003, attached is a proposed Amendment for your consideration. Please review it and call me with your comments

— John P. Scherlacher, Reg. No. 23,009  
Direct Phone No. (213) 337-6846


**FOR INTERNAL PURPOSES ONLY**

**TELECOPY/FAX NUMBER:** (703) 872-9310

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**ATTORNEY BILLING NUMBER:** 71931

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